

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of:

Kenichi SHIRAISHI

Group Art Unit:

US Serial No. 10/589,437

Examiner:

Filed: August 15, 2006

For: EXPOSURE APPARATUS, SUPPLY METHOD AND RECOVERY METHOD,  
EXPOSURE METHOD, AND DEVICE PRODUCING METHOD

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

Sir:

Before examination of the above-identified application, please amend the application as follows: